

Two-Axis Air-Bearing Direct-Drive Linear Stage **PlanarHD**

High Throughput with Ultra-Precise Geometric Performance

The PlanarHD is a high-dynamic, planar-style XY air-bearing stage designed to increase your process throughput while offering the highest possible precision. Engineered to achieve the semiconductor industry's most demanding motion requirements, PlanarHD offers a variety of advanced features and capabilities to give you a competitive advantage.

Key Applications

PlanarHD is ideal for applications that require high dynamics and ultra-high positioning performance, including:

- Semiconductor processing
- Wafer inspection & metrology
- Scanning probe microscopy
- Atomic force microscopy
- Thin film measurement

KEY FEATURES:

- MAXIMIZES THROUGHPUT with velocity to 2 m/s & acceleration to 5 g
- Incorporates active yaw & orthogonality control for MAXIMUM PRECISION
- IMPROVES TURNAROUND TIME with dual linear-motor H-bridge design
- Maintains thermal stability with optional AIR- & WATER-COOLING FEATURES for optimal performance
- Optimizes move-and-settle time & contouring performance with available
 ENHANCED THROUGHPUT
 MODULE
- Available with LASER
 INTERFEROMETER FEEDBACK for best performance at the wafer plane

PlanarHD SPECIFICATIONS

Basic Mode	əl		PlanarHD		
	Scan Axis		500 mm		
	Step Axis		500 mm		
Accuracy (Zero Expansion Scale) ⁽¹⁾			±300 nm		
Repeatability (Long Term)			±50 nm		
XYZ Position Stability (On Air)			20 nm		
Granite Base Thickness			250 mm		
Rated Payload (Maintaining Dynamic Specifications)			5 kg		
Maximum Payload ⁽²⁾			30 kg		
Maximum Velocity with Rated Payload ⁽³⁾		Scan Axis	2000 mm/s		
Peak Acceleration with Rated Payload		Scan Axis	5 g (50 m/s²)		
RMS Acceleration with Rated Payload		Scan Axis	1.25 g (12 m/s²)		
Stiffness, First Natural Frequency, Rated Payload			>330 Hz		
Pitch			3.5 arc sec		
Roll			3.5 arc sec		
Yaw			3.5 arc sec		
XY Orthogonality ⁽⁴⁾			1 arc sec		
MTBF			>40,000 hours		

Notes:

1. Available with Aerotech controllers and calibration.

2. Maximum load based on bearing capability; maximum application load may be limited by acceleration requirements.

3. Maximum speed based on stage capability; maximum application velocity may be limited by system data rate and system resolution.

4. Requires calibration.

5. To protect air bearing against under-pressure, an in-line pressure switch tied to motion controller E-stop input is recommended.

6. Air supply must be clean, dry to 0° F dewpoint and filtered to 0.25 μm or better; recommend nitrogen at 99.9% purity.

7. Travel can be customized to meet application-specific requirements. Consult Aerotech for other travel options.



Representative of custom artifact calibration method.



PlanarHD DIMENSIONS

STAGE	А	В	С	D
PLANAR HD-350-350	350	350	1345	1116
PLANAR HD-350-500	350	500	1345	1266
PLANAR HD-350-650	350	650	1345	1416
PLANAR HD-500-350	500	350	1495	1116
PLANAR HD-500-500	500	500	1495	1266
PLANAR HD-500-650	500	650	1495	1416
PLANAR HD-650-350	650	350	1645	1116
PLANAR HD-650-500	650	500	1645	1266
PLANAR HD-650-650	650	650	1645	1416





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